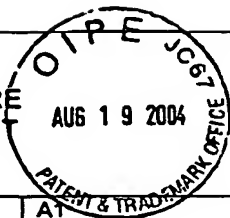


Substitute form 1449A/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

 Sheet **A1** of **A1**
**Complete if Known**

Application Number	10/800,195
Filing Date	03/12/04
First Named Inventor	Dai
Group Art Unit	1752
Examiner Name	Unknown
Attorney Docket Number	5347-218

U.S. PATENTS AND PATENT PUBLICATIONS

Examiner Initials*	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY
		Number	Kind Code (if known)		
SJL ↓	1.	US-6482566		Hofer et al.	11192002
	2.	US-6492259		Dirahoui et al.	12102002

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No.	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	T
		Office	Number	Kind Code (if known)			

OTHER NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T
SJL	3.	Dai et al. "Organoelement resists for EUV lithography," <u>SPIE The International Society for Optical Engineering</u> 4690:1193-1202 (2002)	

Examiner Signature		Date Considered	4-3-05
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.